

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10080848	FILING DATE 02/22/2002	CLASS 257.120	SUBCLASS 706	GAU 1765	EXAMINER Deo
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**APPLICANTS: Ohtake Hiroto; Saitoh Shinobu; Tada Munehiro; Hayashi Yoshihiro;

**CONTINUING DATA VERIFIED:

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** FOREIGN APPLICATIONS VERIFIED:

JAPAN 047358/2001 02/22/2001

2002/0155639

PG-PUB ☒ DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no
35 USC 119 conditions met ☐ yes ☐ no
Verified and Acknowledged Examiners's initials

ATTORNEY DOCKET NO

KRM-00101

TITLE : Method of manufacturing a semiconductor device capable of etching a multi-layer of organic films at a high selectivity

U.S. DEPT. OF COMM. PAT. & TRADEMARK OFFICE, FORM 12-34 94

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED		
		Assistant Examiner	Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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